EFFECT OF ANNEALING ON THE STRUCTURAL AND ELECTRICAL PROPERTIES OF CdTe/ZnTe HETEROJUNCTION THIN FILMS

D. K. DWIVEDI^{*}, DAYASHANKAR^a, MAHESHWAR DUBEY^a

Department of Physics, D.D.U. Gorakhpur University, Gorakhpur- 273009(India) ^aDepartment of Physics, University of Lucknow (India)

Thin film of highly pure (99.999%) CdTe/ZnTe was prepared by high vacuum technique (HVT $5x10^{-6}$ torr), on glass substrates at different substrate temperatures. Thin Films have thickness 0.25 µm. The X-ray diffraction study of the film represents amorphous nature at lower deposition temperature but poly-crystalline nature at higher deposition temperature. The film deposited at lower temperatures was annealed for one hour in vacuum of $5x10^{-4}$ torr at as-deposited to 600K. The annealed film also represents poly-crystalline nature as film deposited at higher substrate temperature, because for all films having different grain sizes, for lower temperature the conductivity is essentially temperature dependent and at higher temperature the potential barriers localized at grain boundaries limit. The electrical conductivity of the film has been measured as a function of temperature. Effect of annealing and deposition rate on the energy band gap have also been studied.

(Received Februyary 11, 2009; saccpted February 15, 2009)

Keyword: Hetrojunction, condensed matter, XRD, DC conductivity, Activation energy, Energy band gap.

1. Introduction

Photovoltaic has the potential to become a major source of energy and to have a significant and beneficial effect on the global environment. Due to its basic optical, electronic and chemical properties, CdTe can become the base material for high efficiency, low cost thin film solar cell [1]. CdTe which is major candidate material for photovoltaics has recently received considerable attention of physicists because of their wide technological applications. The structure of CdTe/ZnTe thin films have been investigated in both the annealed and as deposited states. The X-ray diffraction is used to determine the crystal structure of the layers. Prepared samples are sometimes amorphous and sometimes crystalline depending on evaporation rate about 2θ atomic planes of each constituent per layer. Absence of large range crystalline order are observed even at low temperatures, where as at higher temperature the interface is crystalline [2-4]. Similar works have been done on the thin film of alloys of different compositions of selenium and tellurium regarding the amorphous crystalline transition [5-9]. In this work we report some of our results from as deposited and annealed effect of CdTe/ZnTe thin films which were prepared with equal numbers of closed packed planes of CdTe and ZnTe. Therefore these films were given a post deposition annealing treatment at different temperature in vacuum of 5×10^{-4} Torr. X-ray diffraction was used to characterise the film (amorphous, crystalline or poly-crystalline). The electrical conductivity of CdTe/ZnTe thin film deposited on glass substrate are studied as a function of

^{*}Corresponding author: dwivedidkphys@rediffmail.com

temperature. Activation energy, conductivity and energy band gap have been determined. Similar work on conductivity measurement of thin film of CdTe has been done by other workers [10, 11].

2. Experimental procedure

2.1 Sample preparation

Thin films of Cadmium telluride and Zinc telluride of thickness 0.25 μ m were prepared by electron beam evaporation of 99.999% purity chemicals on optically plane pyrex glass substrate of dimensions 2.0cm x 7.0cm x 2mm under the vacuum of order of 10⁻⁶ torr at 300K, 350K and 400K. Films of CdTe / ZnTe deposited at 350K were annealed in vacuum 5x10⁻⁴ Torr at the temperature as-deposited, 450K, 500K and 600K for one hour. Before deposition glass substrate were cleaned using teepol detergent, isopropyle alcohol and distilled water in sequence [3-9, 12, 13]. The source to substrate distance during vacuum deposition of the film was 15 cm. The thickness of the film was measured using a quartz crystal thickness monitor. In order to ensure the correct composition of the film formed in each evaporation, a known quantity of the material was taken in the crucible and was evaporated completely at a fast rate. All the evaporation was carried out in nearly identical deposition conditions.

2.2 Structural and electrical properties

X-ray diffraction was performed in symmetric reflection geometry, when the scattering vector is perpendicular to the plane of sample, and symmetric transmission geometry when the scattering vector lies in the plane of the sample. The layer structure of the films were determined by X-ray diffraction (PHILLIPS PW 1700) using Ni-filtered Cu-K α (λ =1.54 Å) radiation. Fig.1 shows large angle (2 θ = 20°-90°) diffraction patterns of CdTe/ZnTe. Electrical D.C. conductivity of the CdTe/ZnTe hetrojunction thin films has been measured using four probes method.



Fig. 1. X-ray diffraction pattern of CdTe/ZnTe thin film of thickness 0.25 µm deposited at (a) 300K, (b) 350K and (c) 400K

3. Result and discussion

3.1 Crystallization properties I

XRD studies were carried out in order to get an idea about the structure of CdTe/ZnTe Thin films. CdTe/ZnTe structures were determined by a large angle ($2\theta = 20^{\circ}-90^{\circ}$, $\lambda=1.54$ Å) X-ray diffraction pattern. To study the effect of substrate temperature, the X-ray diffraction measurements were carried out on film deposited at 300 K, 350K and 400K of thickness 0.25µm respectively and is shown in Fig.1. The films were found to be sometimes amorphous and sometimes crystalline, perhaps depending on the substrate temperature of the films. At lower temperature films are amorphous. Film deposited at 400K was found to be poly-crystalline in nature along the peak intensity direction as shown in Fig.1. It is found that films deposited at higher temperatures have better crystallinity and crystallization happens in CdTe/ZnTe both the materials. Also film stack still exist after annealing, and at a particular temperature (260 K) a mixed crystalline layer is formed [13, 14]. The intensities for various planes were estimated by measuring peak heights directly with diffractometer chart.

3.2 Crystallization properties II

To identify the crystalline phase, as well as crystalline forms of CdTe/ZnTe thin films, it was subjected to annealing at as-deposited, 450K, 500K and 600K for one hour in vacuum of order of 5×10^{-4} Torr. The annealing temperatures were selected to be between glass transition and crystalline temperature as drawn out from DTA traces. After each step of annealing the X-ray diffraction was recorded with the diffraction angle 20, range 20°-90°. Among obtained traces of the sample, trace (a) is characteristic to amorphous state, as illustrated in Fig .2.



Fig.2. X-ray diffraction pattern of CdTe/ZnTe thin film of thickness 0.25 μm deposited at 300K annealed one hour in vacuum of 5x10⁻⁴ torr at different temperatures (a) as-deposited, (b) 450K, (c) 500K and (d) 600K.

Fig.2 shows that X-ray peak roots start to grow at different angle within the selected range. The X-ray peak roots continue to grow as the temperature of annealing increases in the successive annealing step. The peaks were selected to investigate the crystalline phase and crystalline structure of each phase as shown in Fig.2.

The main crystalline phase of CdTe / ZnTe obtained, were well matched by the American Society for Testing and Materials (ASTM) Cards. It is also observed from Fig.2 that the peak height increases while the peak width decreases with higher annealing temperature. The growth of the peak as a function of the annealing temperature may be attributed to the growing up of the crystalline phase of the virgin films. The crystalline in turn, leads to the decrease of the activation energy and the decrease of the energy barrier between the neighboring sites [10].

3.3 Electrical properties

3.3.1 Temperature dependence of DC conductivity of CdTe / ZnTe thin film

The temperature dependence of conductivity of CdTe/ZnTe hetrojunction thin film of thickness 0.25 μ m deposited on glass substrate and at different substrate temperatures 300, 350 and 400K, are shown in Fig.3. It is seen from the plot that for all the films, the conductivity is a linear function of the reciprocal temperature, decreases with decreasing temperature, in the temperature range studied. Linearity of the plot is nearly same for all the films. The activation energy is evaluated from the slope of log σ versus 1/T plot in the higher temperature range. The activation energy is found to vary between 110 to 780 meV. After annealing conductivity measurements were performed on amorphous CdTe/ZnTe thin film as a function of 1/T in the range 300 to 600 K. The conductivity during the cooling cycle closely coinsides with that in heatings cycle. However, for all of calculations, we have used data of films during the cooling cycle.



Fig.3. Log σ versus $10^3/T$ of CdTe/ZnTe hetro junction thin film of thickness 0.25 μ m deposited at (a) 300K, (b) 350K and (c) 400K.

The thermal activation energy of film was determined from the slope of log σ versus 1/T plot as shown in Fig.3 using the relation $\sigma = \sigma_0 e^{(-Ea/KT)}$. It is evident from the Fig.4 (plots a, b, c), that the slop vary within a narrow range for the different films. Further we observed a decrease in the conductivity of sample annealed at a high temperature which may be due to higher ordered structures (less defects). The annealing also provides crystallinity of the amorphous samples (prepared at 300K) as evident from the pronounced peaks in the XRD pattern.



Fig. 4. Log σ versus $10^3/T$ of CdTe/ZnTe hetro junction thin film of thickness 0.25 μ m deposited at 300K, annealed one hour in vacuum of $5x10^{-4}$ torr at different temperatures as-deposited, (b) 450K, (c) 500K and (d) 600K.

3.3.2. Deposition rate and annealing dependence of energy band gap

The variation of energy band gap with the deposition rate in CdTe/ZnTe hetrojunction thin film is shown in Fig.5.The change in energy band gap with deposition rate Rd is marginal upto the deposition rate of 30 Å S⁻¹, above which it decreases sharply to 3.54 eV.



Fig.5. The variation of energy band gap (E_g) *with deposition rate.*

This change in energy band gap can be attributed to the structural disorder or defect at the grain boundries of the layers as discussed above as well as the higher tensile strain in the films grown at higher deposition rate [12, 15, 16]. It is found that annealing results in the breaking of homo nuclear bonds and formation of energetically more favored hetronuclear bond. In this way

due to annealing the random network is partially changed approaching a more ordered structure. This transfer is accompanied by decrease of band gap with deposition rate. It is expected that annealing of the layer might increase the band gap as the annealing process could decrease the disorderedness present in the layers.

4. Conclusions

CdTe / ZnTe hetrojunction thin films have been successfully fabricated using electron beam deposition technique on smooth photographic Pyrex glass substrate at different substrate temperatures. Films have been annealed in vacuum $5x10^{-4}$ torr for one hour at as-deposited to 400K, 500K and 600K respectively. Further systematic X-ray diffraction investigations give more information about the dislocation, densities, etc. The layer structure has been confined by large angle 20°-90°, 20 X-ray diffraction studies. The studies show that the film deposited at 400K give better poly-crystalline nature. Conductivity of the film decreases with decreasing the temperature. It is found that energy band gap of CdTe/ZnTe hetrojunction thin film decreases with deposition rate.

Acknowledgement

We are thankful to Prof M.H.Khan, Head Deptt of Physics Jamia Millia Islamia University, New Delhi for providing necessary help in carrying out experimental work, Thanks are also due to Prof J.P.Gupta Ex Head Deptt of physics D.D.U.Gorakhpur University, Gorakhpur for his constant encouragement.

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